

AMENDMENTS TO THE CLAIMS:

Please amend Claims 22 and 25-33 as follows:

1-21. (Cancelled)

22. (Currently Amended) A pod ~~capable of including a substrate attachable to an outside surface of an electromagnetic-shielded chamber which covers a device manufacturing apparatus, the device manufacturing apparatus importing a substrate from said pod, said pod comprising:~~

~~walls which form the opening; and~~

~~a lid for the an opening defined by the walls, the substrate in said pod being imported to the device manufacturing apparatus through the opening; and,~~

~~wherein said walls comprise an electromagnetic shield member, which is provided by said walls, at least and a portion of said electromagnetic shield member being provided on said walls so as to contact the electromagnetic shielded chamber so that said is arranged on a part of said walls which contacts the electromagnetic shield member is grounded through the electromagnetic-shielded chamber.~~

23. (Previously Presented) A pod according to Claim 22, wherein said lid is arranged in front of said pod.

24. (Previously Presented) A pod according to Claim 22, wherein said lid is arranged in a bottom of said pod.

25. (Currently Amended) A pod according to Claim 22, wherein said electromagnetic shield member comprises wire mesh ~~provided~~ arranged on or within said walls.

26. (Currently Amended) A pod according to Claim 22, wherein said electromagnetic shield member comprises metal coatings ~~provided~~ arranged on said walls.

27. (Currently Amended) A pod according to Claim 22, wherein said electromagnetic shield member comprises electromagnetic-shield materials ~~provided~~ arranged in said walls.

28. (Currently Amended) -An apparatus for manufacturing a device using a substrate, said apparatus comprising:

an electromagnetic-shielded chamber;
~~an importing handling unit which imports the substrate through an opening of into a pod pressed against said electromagnetic-shielded chamber from a pod attached to an outside surface of said electromagnetic chamber;~~ and

a processing unit which ~~processes~~ performs a process using the substrate imported by said ~~importing handling~~ unit;

wherein said electromagnetic shielded chamber has a grounded portion, against

~~which the pod is to be pressed, of said electromagnetic-shielded chamber is grounded for contacting the pod.~~

29. (Currently Amended) An apparatus according to claim 28, wherein said grounded portion is provided arranged around an opening a door of said electromagnetic-shielded chamber through which said importing handling unit imports the substrate.

30. (Currently Amended) An apparatus according to Claim 28, wherein said processing unit has a function of exposing the process performed by said process unit is exposure of the substrate to a pattern.

31. (Currently Amended) An apparatus according to Claim 28, wherein a lid for the opening of the pod is arranged in front of the pod.

32. (Currently Amended) An apparatus according to Claim 28, wherein a lid for the opening of the pod is arranged in a bottom of the pod.

33. (Currently Amended) An apparatus according to Claim 28, wherein walls of the pod comprises an electromagnetic shield member is provided by the walls of the pod.

Claims 34 through 37. (cancelled)

38. (Withdrawn) A device manufacturing method comprising a step of transferring a substrate using a pod defined in Claim 22.

39. (Withdrawn) A device manufacturing method comprising a step of processing a substrate using an apparatus defined in Claim 28.

40. (Withdrawn) A method according to Claim 39, wherein in said processing step, the substrate is exposed to a pattern.